HW5 31/12/24, 01:50

### **Abstract**

This carrier quantum-confinement simulation of Silicon (Si) inversion layer, pertains to a 1D MOS Capacitor at 300K, using COMSOL's 'Multiphysics®' and nanoHUB's 'Schred 1.0' tool. Such a simulation requires calculating the carrier concentration (in this case electron) as a function of vertical distance from the oxide-channel interface (referred to as 'Arc length' in the upcoming plots), based on standard MOS device parameters (referred from [1] COMSOL Documentation) and carrier transport formalisms such as -

- 1. Density Gradient: based on a quantum potential-corrected continuum transport description of carriers, as originally formulated in [2].
- 2. Schrödinger-Poisson: based on a full quantum transport description of carriers using non-equilibrium Greene's function, as originally formulated in [3].

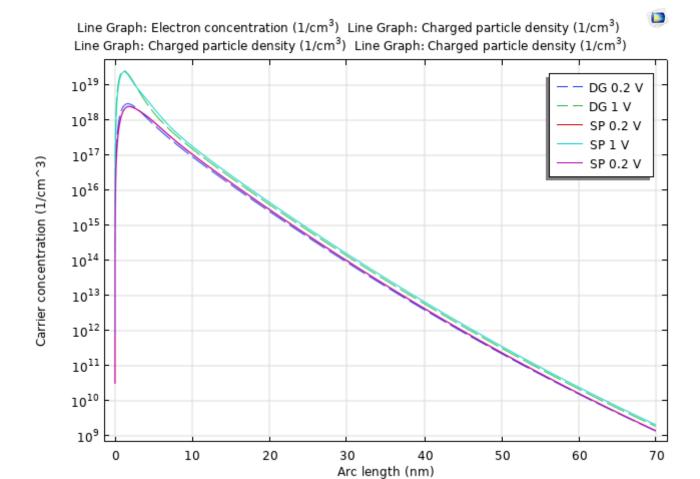
### **Table of Contents**

- Part I: Density-Gradient and Schrödinger-Poisson solution of inversion layer, using COMSOL
  - Simulations at  $V_q=0.2V,\,1V$ 
    - Summary
- Part II: Schrödinger-Poisson solution of inversion layer, using NanoHUB and COMSOL
  - ullet Simulations at  $V_q=1V$ 
    - Summary
- Part III: Classical-Poisson solution of inversion layer, using NanoHUB and COMSOL
  - ullet Simulations at  $V_q=1V$  (in NanoHUB) and  $V_q=0.2V,1V$  (in COMSOL)
    - Summary
- References

# Part I: Density-Gradient and Schrödinger-Poisson solution of inversion layer, using COMSOL

Simulations at  $V_g=0.2V, 1V$ 

iW5 31/12/24, 01:50



	Density-Gradient solution ( $V_g$ = 0.2V, 1V)	Schrödinger-Poisson solution ( $V_g$ = 0.2V)	Schrödinger-Poisson solution ( $V_g$ = 1V)
Time elapsed (s)	9	72	101
Memory usage (GB)	1.01	1.09	1.27

#### Summary

- 1. As noted in the table above (and as mentioned in [2]), the Density-Gradient formulation is more computationally efficient than Schrödinger-Poisson formulation in solving carrier concentrations (and with similar solutions w.r.t that of Schrödinger-Poisson formulation  $\forall V_g$ , as observed in the plot above) across the vertical Si channel.
- 2. Both formulations capture the effect of electron quantum-confinement near 3-4 nm range  $\forall V_g$  (observed as peaks in the plot above). This effect is due to -
  - Electron quantisation in the Si channel stemming from a degenerate Si bandstructure.
  - Increasing potential barrier height at the oxide-channel interface due to ever decreasing oxide thickness (which has to do with MOS process node scale-down), leading to zero probability of electron tunneling into the oxide.

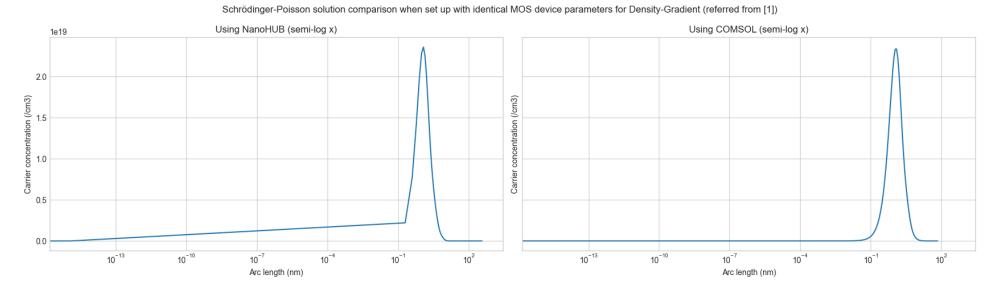
# Part II: Schrödinger-Poisson solution of inversion layer, using NanoHUB and COMSOL

# Simulations at $V_g=1V$

```
In [2]:
 SPNanoHUB = pd.read_csv('Part II/3.txt', skiprows=4, nrows=999, header=None)
           pd.read_fwf('Part I/2.txt', skiprows=8, nrows=199, header=None)
 fig,axes = plt.subplots(nrows=1,ncols=2,tight_layout=True,sharex=True,figsize=(17, 5))
 fig.suptitle('Schrödinger-Poisson solution comparison when set up with identical MOS device parameters for Density
plt.subplot(121)
plt.plot(SPNanoHUB[0],SPNanoHUB[1])
plt.xscale('log')
axes[0].set_xlabel('Arc length (nm)')
axes[0].set_ylabel('Carrier concentration (/cm3)')
axes[0].set_title('Using NanoHUB (semi-log x)')
plt.subplot(122)
plt.plot(SPCOMSOL[0],SPCOMSOL[1])
plt.xscale('log')
axes[1].set_xlabel('Arc length (nm)')
axes[1].set ylabel('Carrier concentration (/cm3)')
axes[1].set title('Using COMSOL (semi-log x)')
```

W5 31/12/24, 01:50

Out[2]: Text(0.5, 1.0, 'Using COMSOL (semi-log x)')

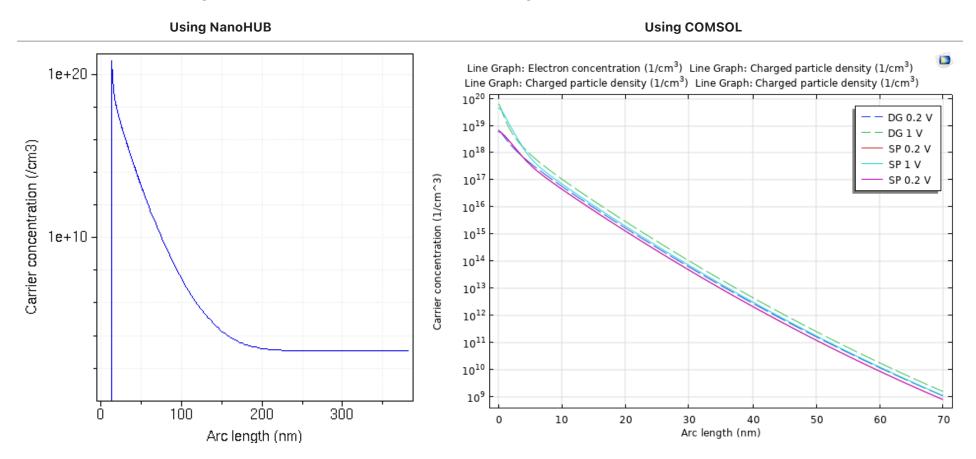


#### Summary

- 1. Both NanoHUB (Schred tool) and COMSOL capture the electron charge centroid (peaks in the plots above) at the same position in the vertical Si channel, which indicates that the Schrödinger-Poisson formulation in both tools are similarly defined.
- 2. The slight discreteness in the NanoHUB plot above indicates a lack of enough discretisation nodes defined along the vertical Si channel in the Schred tool.

# Part III: Classical-Poisson solution of inversion layer, using NanoHUB and COMSOL

Simulations at  $V_g=1V$  (in NanoHUB) and  $V_g=0.2V, 1V$  (in COMSOL)



HW5 31/12/24, 01:50

#### **Summary**

- 1. To perform a Classical-Poisson simulation of the inversion layer:
  - <u>Using NanoHUB Schred</u>: As noted in page 11 of [4], Schred 2.0 with the semiclassical charge model is used and the resulting simulation plot is shown in the left above.
  - <u>Using COMSOL</u>: As inferred from [1] and based on the discussion in point 2 of Summary in Part I) -
    - A. For classical approximation from Density-Gradient formulation: electron mass (meDG) is set to 10xme\_const/3 (inferred from page 7 of [1]), and n barrier height at oxide interface ( $\Phi_n^{Ox}$ ) is set to 0 (inferred from page 8 of [1]).
    - B. For classical approximation from Schrödinger-Poisson formulation: Zero Probability node in the COMSOL model tree is disabled (inferred from page 13 of [1]).
    - C. The combined resulting simulation plot (classical approximation from Density-Gradient \& Schrödinger-Poisson formulations) is shown in the right above.
- 2. Both plots above (Classical-Poisson simulations using NanoHUB and COMSOL) indicate a monotonically decreasing inversion electron concentration from the oxide-Si channel interface (non-existent electron charge centroids at further depths in the vertical Si channel), which is the case when there is no carrier quantum-confinement effect.

### References

- [1] COMSOL Documentation Density-Gradient and Schrödinger-Poisson Results for a Silicon Inversion Layer
- [2] Density-gradient theory: a macroscopic approach to quantum confinement and tunneling in semiconductor devices M.G. Ancona
- [3] Nanoscale device modeling: the Green's function method Supriyo Datta
- [4] Schred Documentation Quantum Size Effects and the Need for Schred Dragica Vasileska

## Additional information

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Data and config file at: Github